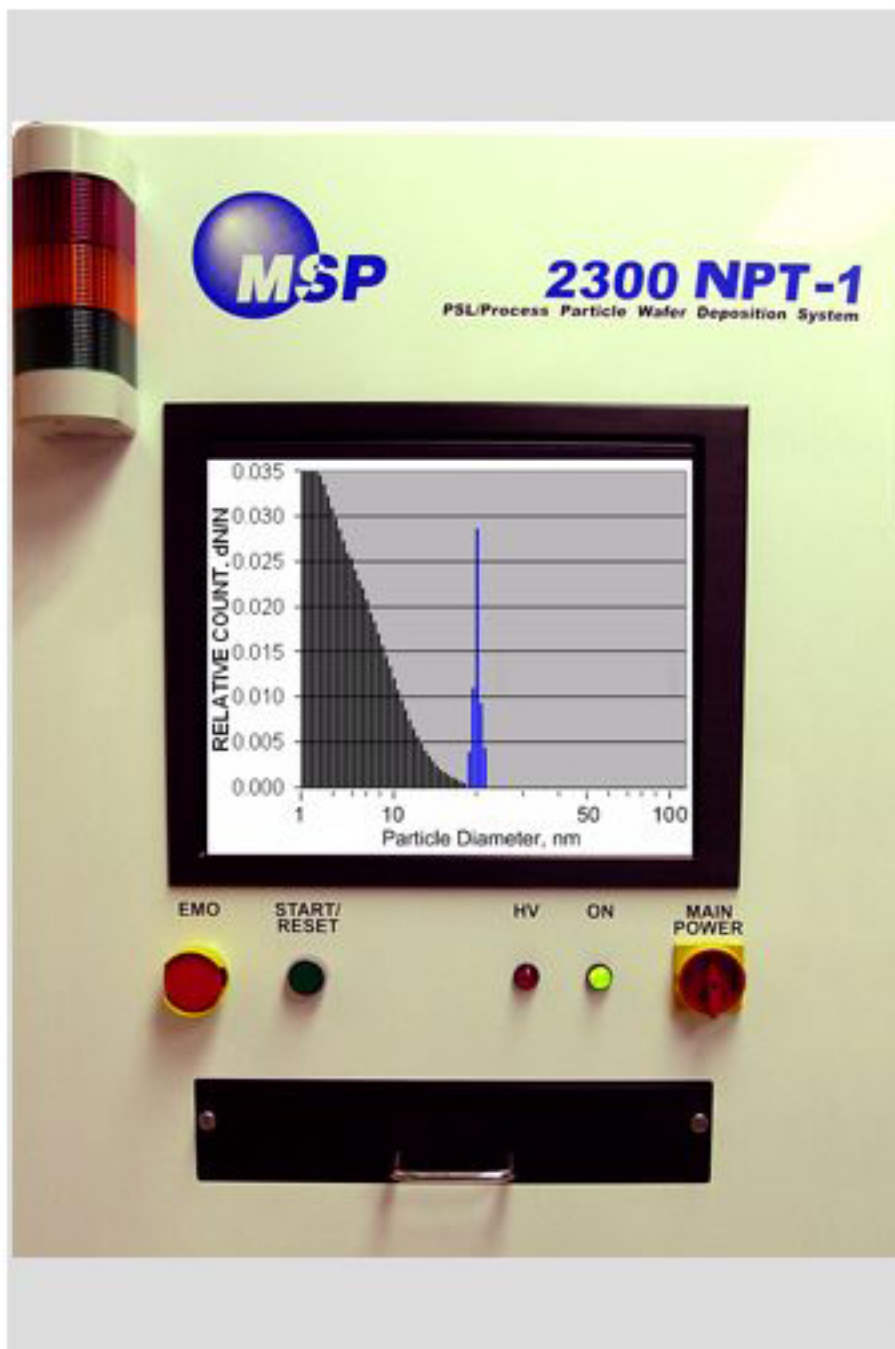


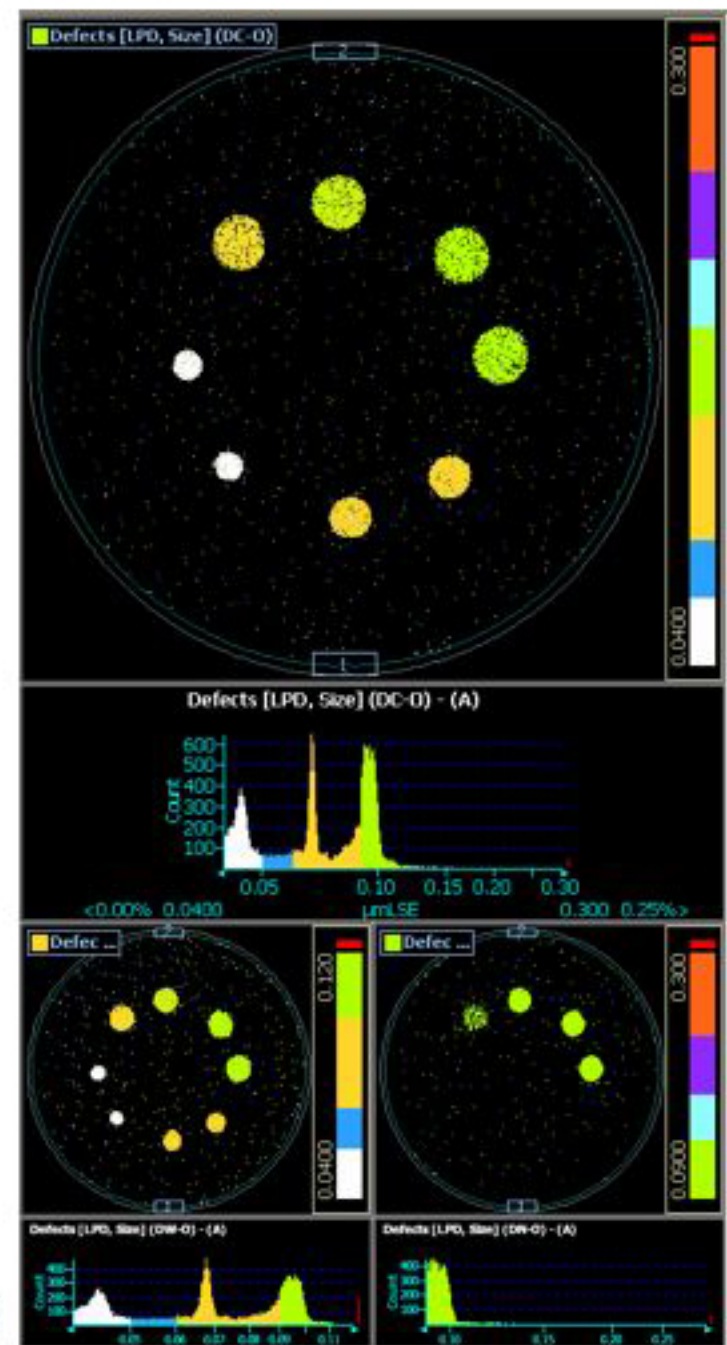
Model 2300 NPT-1 Particle Deposition System

*Nano Particle Technology to Produce Highly
Accurate, NIST Traceable, PSL Wafer Standards
for Wafer Inspection Systems: 20nm - 2 μ m*



NPT-1
47nm,
81nm
NIST
100.7nm
Deposits

Is Your
Wafer
Inspection
System
Out of
Calibration?



**Recipe Control; 10 Quick Change PSL Sizes; NIST
SRM Calibration Mode; Exceeds SEMI M52 Size
Accuracy; Full, Spot & Ring Depositions; CE
Mark, SEMI S2, S8, S14**



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